

# Investigation of Surface Plasmon Resonance of Ag films capped with Cs<sub>2</sub>O Layers

George Schwartz, 3<sup>rd</sup> Yr. CSS Scholar

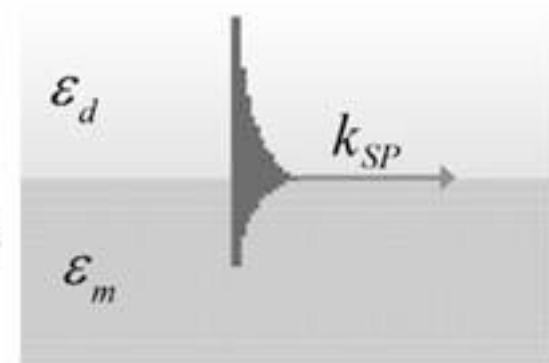
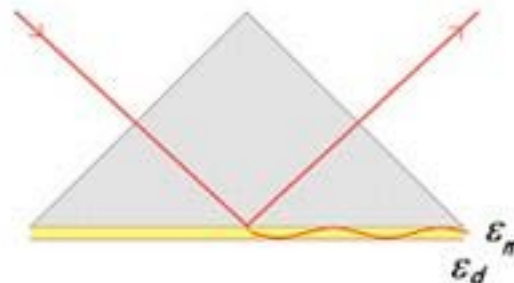
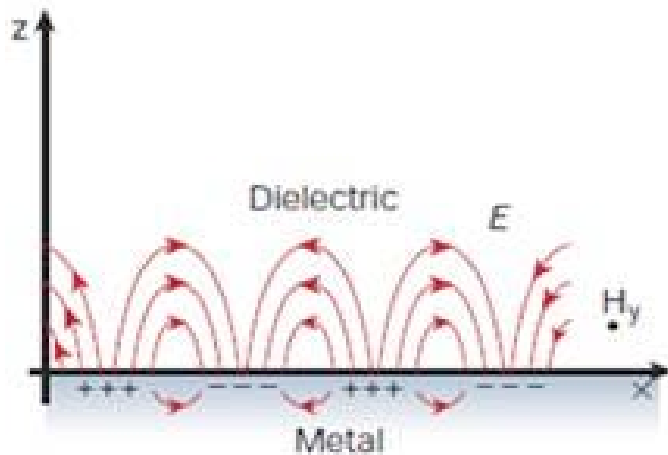
Advisor: Professor R. A. Lukaszew

Collaborators: Zhaozhu Li, Matt Heimburger



# Surface Plasmon Resonance

- \* Oscillations of electrons in a metal resulting in evanescent electromagnetic waves which propagate along a metal/dielectric interface



# Exciting the SPR

- \* SPR may be excited the dielectric constants  $\epsilon_m$  (metal) and the  $\epsilon_d$  (dielectric) satisfy a dispersion relation:

$$K(\omega) = \frac{\omega}{c} \sqrt{\frac{\epsilon_1 \epsilon_2 \mu_1 \mu_2}{\epsilon_1 \mu_1 + \epsilon_2 \mu_2}}$$

- \* SPR can occur if:

$$\text{Re}[\epsilon_m] < 0$$

$$\text{Re}[\epsilon_d] < -\text{Re}[\epsilon_m]$$

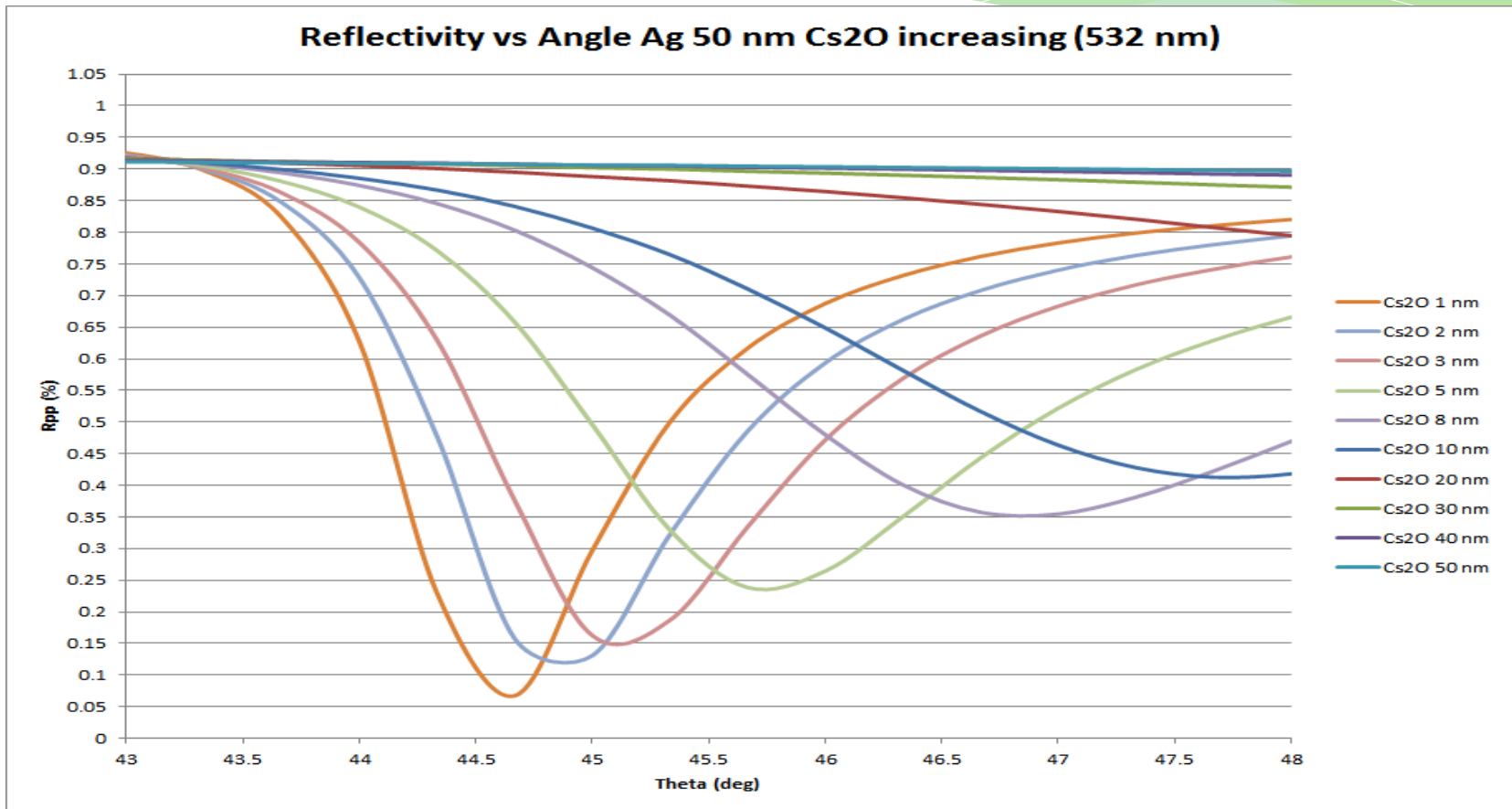
- \* Additionally, only can excite the SPR by matching the wave vector of the surface plasmons,  $k_{sp}$ , with that of incident light,  $k_o$  (matching momentum)
  - \* Note:  $k_{sp} > k_o$  always!
  - \* So an optical coupler (prism/grating) is needed to increase  $k_o$

# Applications

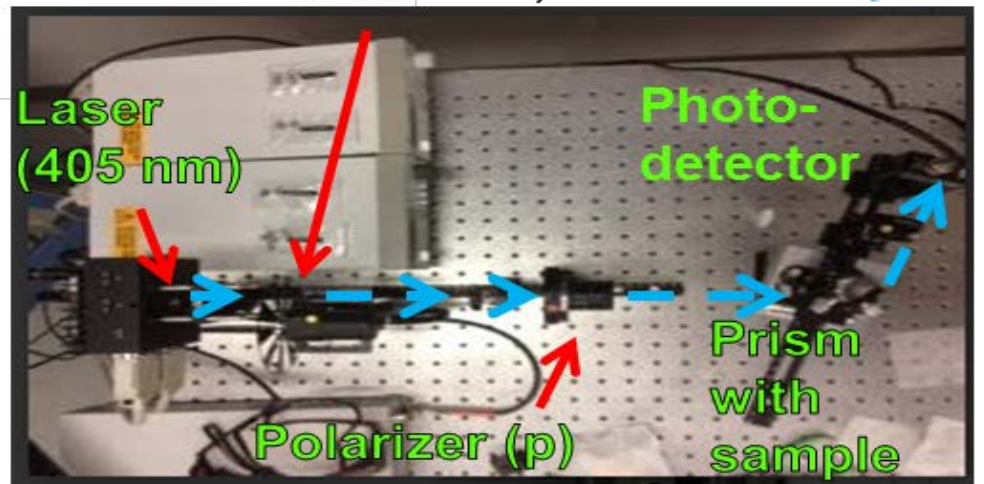
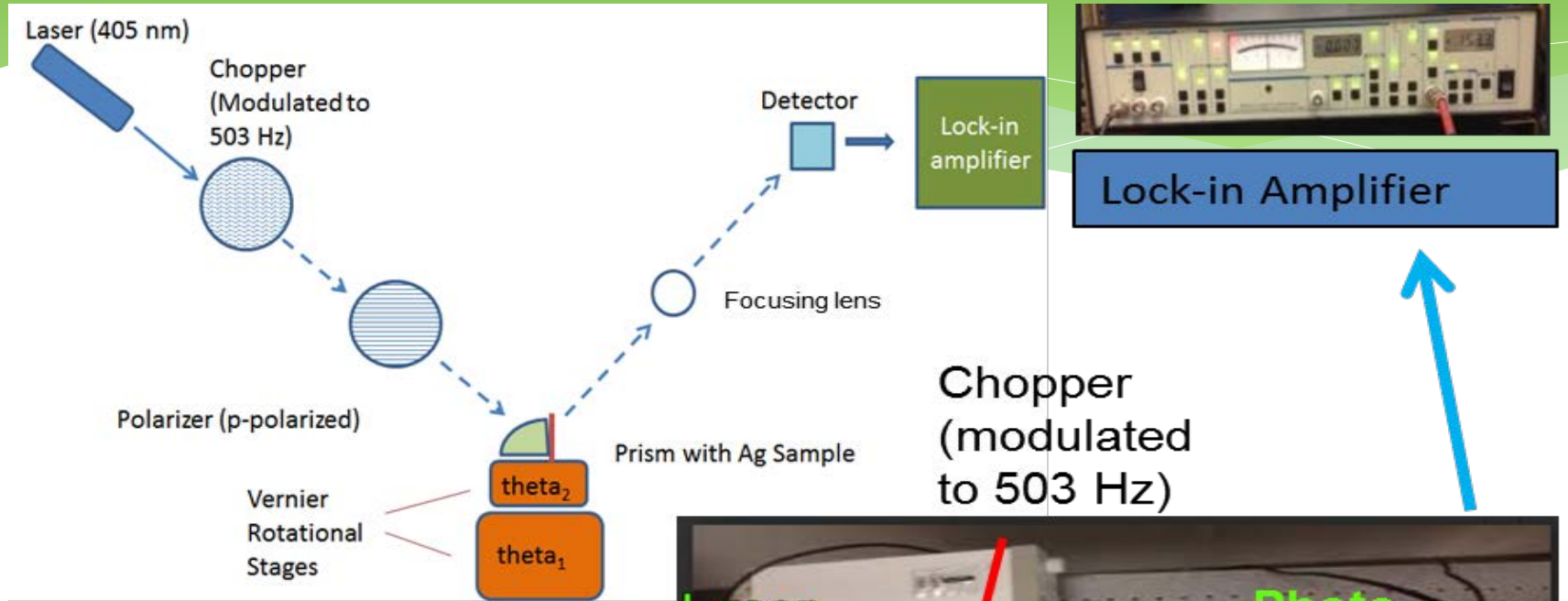
- \* Surface Plasmon Resonance is highly dependent on the incident light's wavelength, angle, and the material composition (metal / dielectric surfaces)
- \* Can exploit these properties to enhance metallic photocathodes
- \* Metallic Cathodes:
  - \* PRO: Robust (last years), <ps response time
  - \* CON: Low Quantum Efficiency (<<1%)
- \* Semi-conductor Photocathodes:
  - \* PRO: QE (5-50%)
  - \* CON: Short lifetimes (days-months), Long response times
- \* Applicable for High Energy Electron Colliders

# Simulation

- \* Prior to physically testing the SPR, we simulated how the reflectivity changed based off incidence angle and film thickness.

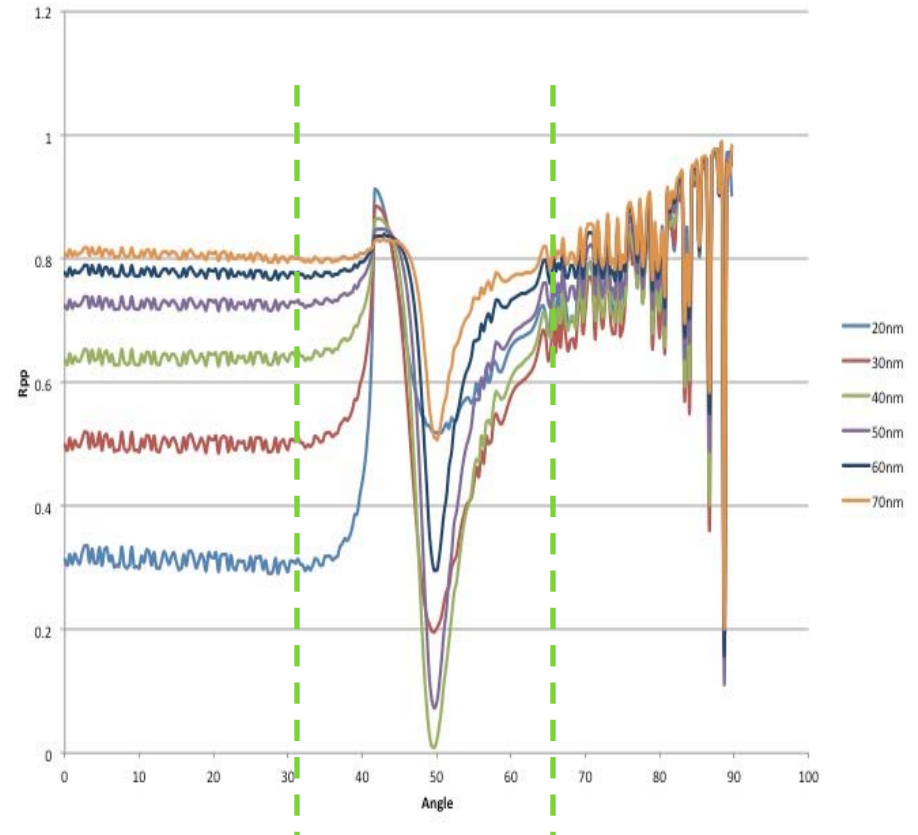


# Optical Set-up



# SPR Results

- \* After the set-up was fully aligned, we tested it for Ag (40 nm) films for 405 nm blue light and compared it to the simulation.



# Future Steps

- \* Investigation of  $\text{Cs}_2\text{O}$  properties (dielectric constant) and lowering the work function of Ag films
- \* Adjusting the simulation of Ag/ $\text{Cs}_2\text{O}$  for 405 nm light as a standard of comparison for future experimental data
- \* Deposition at oblique incidence to improve the precision of the SPR dip



# Acknowledgements

- \* I would like to thank Professor Lukaszew for being an amazing mentor, both with the research and teaching me valuable life lessons
- \* My co-workers Zhaozhu Li and Matt Heimburger for integrating me into the project and assisting me throughout the summer
- \* VMEC foundation for providing funding for this summer's research
- \* The College Science Scholars Program